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INFORMATION DISCLOSURE STATEMENT

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Sheet 1 of 1

Form PTO-14 (Rev. 2-88)

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE 5853-223

ATTY. DOCKET NO. APPLICATION NO. 1<u>0/</u>081,979

APPLICANT SINGH, et al.

FILING DATE

2/22/02

U.S. PATENT DOCUMENTS

EXAMINER'S INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	6,063,306	5/16/00	Kaufman, et al.			
	5,954,997	9/21/99	Kaufman, et al.			
	6,126,853	10/3/00	Kaufman, et al.			
	5,863,307	1/26/99	Zhou, et al.			
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	6,290,736 B1	9/18/01	Evans			
		FOREIGN PATEN	T DOCUMENTS	<u> </u>	L	

DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION		
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EP 0 913 442 A2	06.05.1999	Europe	C09G 1/02, C09K 3/14 //B24B37/04				
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	·			<u> </u>			
	OTHER DOCU	MENTS (Includ	ling Author, Title, Date, Pertine	nt Pages, E	tc.)		

Stöber, W., et al. "Controlled Growth of Monodisperse Silica Spheres in the Micron Size Range", Journal of Colloid and Interface Science, Vol. 26 (1968), pgs. 62-69;
Rosen, M.J., "Surfactants and Interfacial Phenomena"John Wiley & Sons, 1989, pgs. 3-32, 52-54, 70-80, 122-132 and 398-401; and
 Singh, R.K., et al., "Chemical-Mechanical Polishing 2000-Fundamentals and Materials Issues, Vol. 613, 2000, pgs. E7.8.1-E7.8.6. (Months)

EXAMINER DATE CONSIDERED 6/25/03

EXAMINER: Initial if a citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.